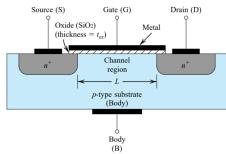
Maybe there is something here not again



The size of the "process" indicates the minimum possible channel length.

Magnitude of the electron charge in the channel [Q]:

$$|Q| = C_{OX}(WL)v_{OV}$$

 $|Q| = C_{OX}(WL) v_{OV} \label{eq:cox}$ C_{OX} is the oxide capacitance, $[{\rm F/m^2}]$

$$C_{OX} = \frac{\epsilon_{OX}}{t_{OX}}$$

 ϵ_{OX} is the permittivity of the SiO₂. t_{OX} is the oxide thickness.

For C_{OX} per micron squared, use $C = C_{OX}WL$ [fF]

$$i_D = \left[\left(\mu_n \, C_{OX} \right) \left(\frac{W}{L} \right) \left(v_{GS} - V_t \right) \right] v_{DS}$$

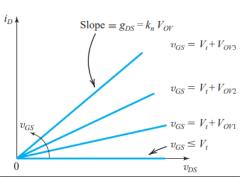
$$i_D = \left[g_{DS}\right] v_{DS}$$

$$k_n' = \mu_n C_{OX}$$

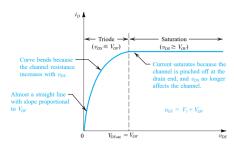
$$k_n = k_n'(W/L)$$

When V_{DS} is small, the MOSFET behaves as a linear resistance r_{DS} whose value is controlled by the gate voltage v_{GS} .

$$r_{DS} = \frac{1}{g_{DS}}$$



Triode vs Saturation



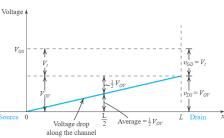
Triode $(v_{DS} \leq V_{OV})$

$$i_D = k_n^{'} \left(\frac{W}{L}\right) \left(V_{OV} - \frac{1}{2} v_{DS}\right) v_{DS}$$

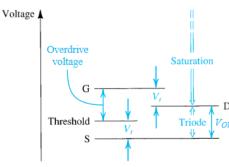
$$i_D = k_n^{'} \left(\frac{W}{L}\right) \left[(v_{GS} - V_t) v_{DS} - \frac{1}{2} v_{DS}^2 \right] \label{eq:ideal}$$

Saturation $(v_{DS} \ge V_{OV})$

$$i_D = \frac{1}{2} k_n' \left(\frac{W}{L}\right) V_{OV}^2$$



Constant V_{OV} can be replaced by variable v_{OV} . PMOS transistors operate similarly but the polarity is reversed, so v_{GS} must be negative and larger than a negative v_{tp} , as is v_{DS} negative.



If you care about ${\bf channel\text{-}length}$ ${\bf modulation},$ then use the expression:

$$\begin{split} i_D &= \frac{1}{2} k_n^{'} \left(\frac{W}{L} \right) \left(v_{GS} - V_{th} \right)^2 (1 + \lambda v_{DS}) \\ v_{DS} &= -\frac{1}{\lambda} \mid V_A = \frac{1}{\lambda} \mid V_A = V_A^{'} L \\ V_A \text{ has units of volts.} \\ V_A^{'} \text{ has units of volts per micron.} \end{split}$$

